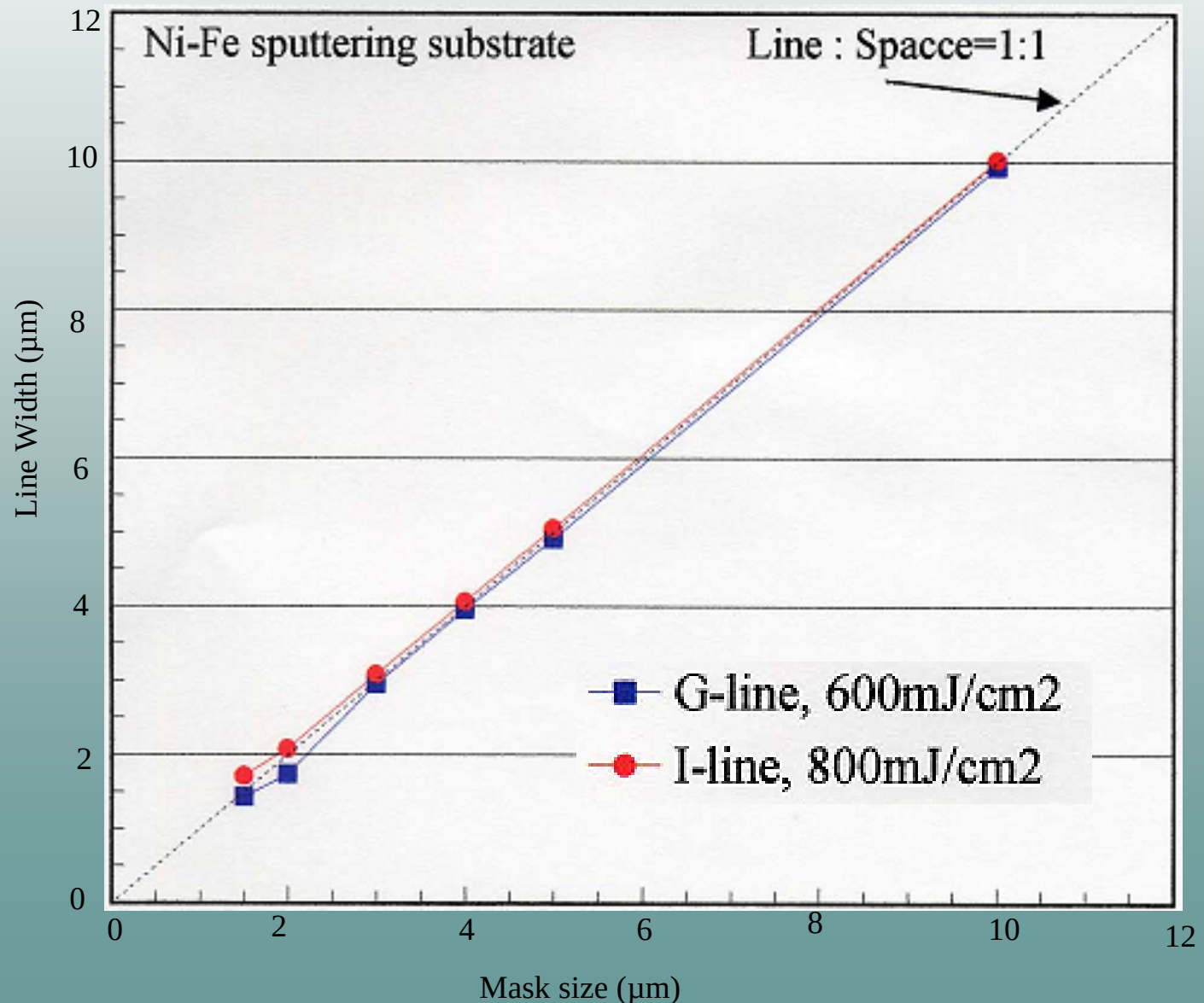
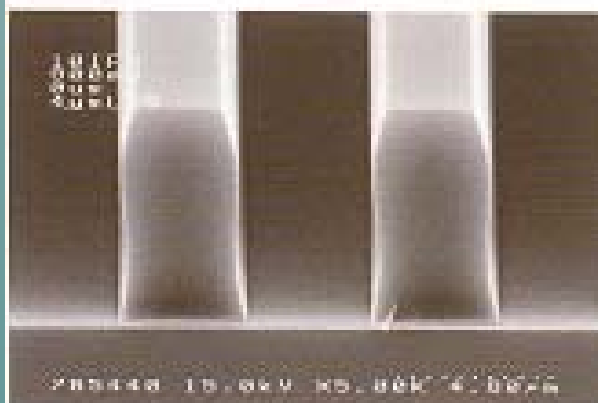
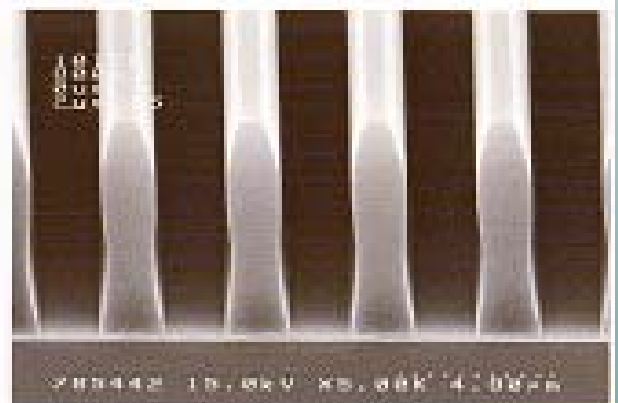
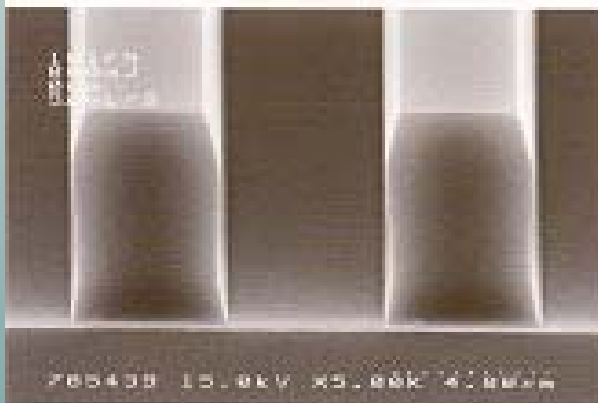
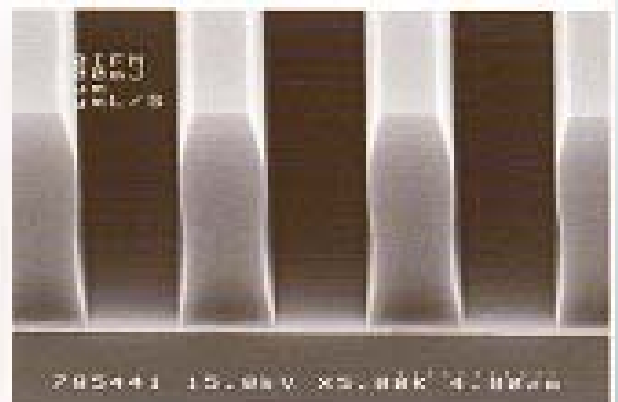
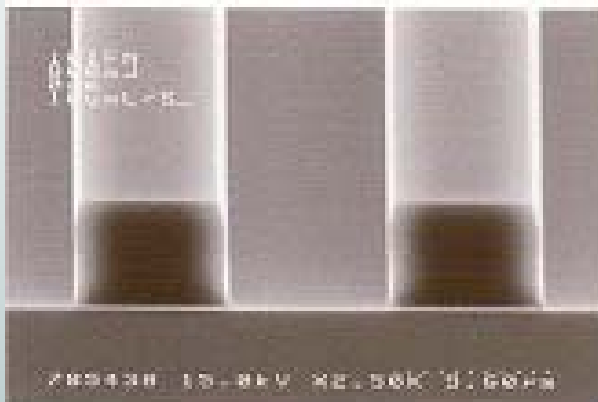


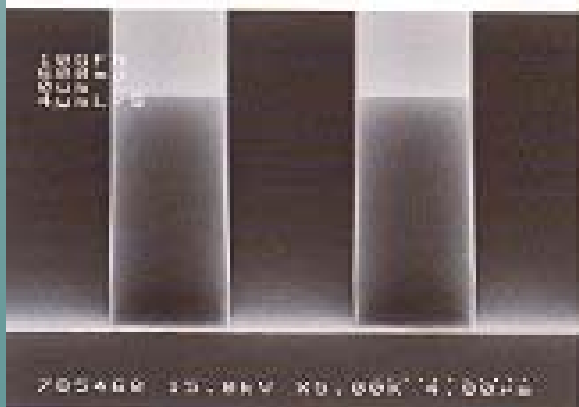
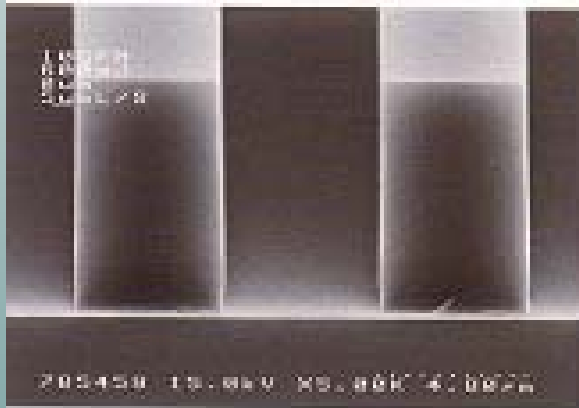
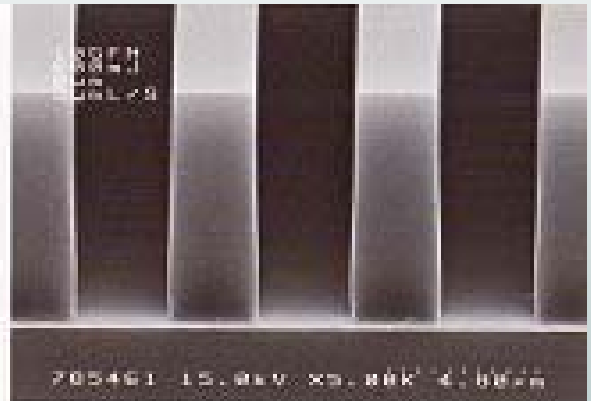
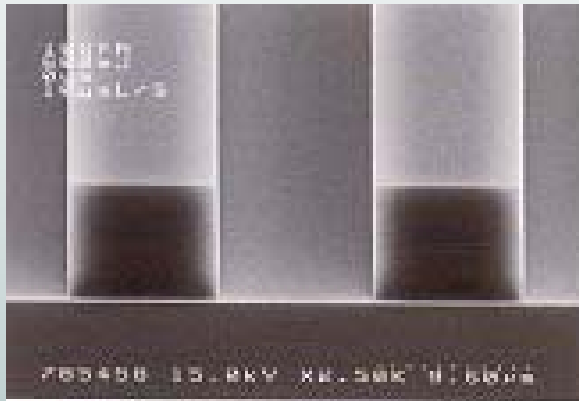
Film Thickness: 10 μ m Prebake: 100°C x 120 sec
 Exp.: G-line NSR-TFHI (NA = 0.22, s = 0.60)
 I-line NSR-1755i7A (NA = 0.50, σ = 0.60)
 PEB: none Focus : 0 μ m
 Dev.: 50 sec x 5 (SSFD-238 [TMAH = 2.38%])



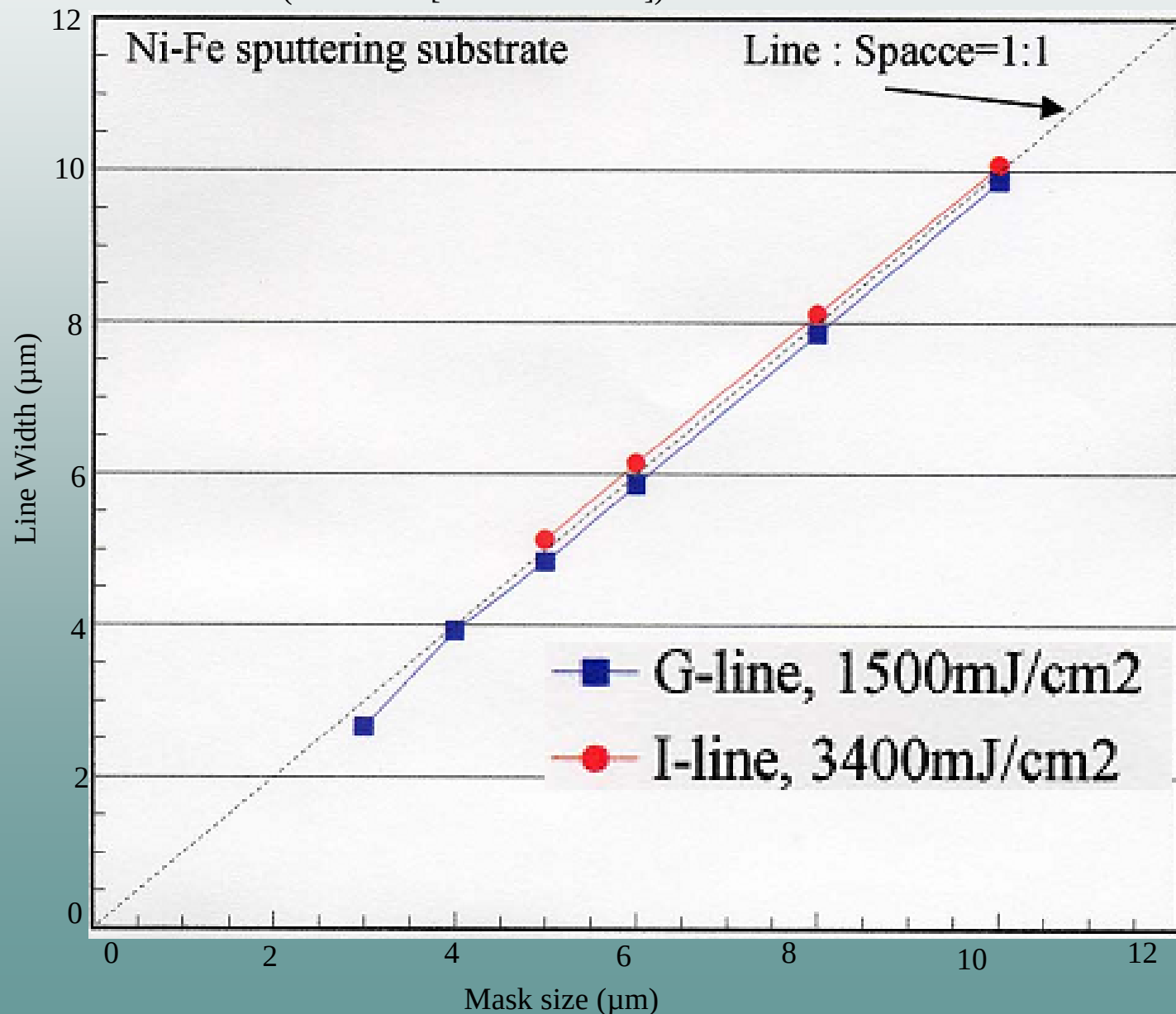
Film Thickness: 10 μ m Prebake: 100°Cx120 sec
Exp.: NSR-1755i7A NA = 0.50, σ = 0.60 800mJ/cm²
PEB: none Focus : 0 μ m Mask size: 10,5,4,3,2 μ m L/S
Dev.: 50 sec x 5 (SSFD-238 [TMAH = 2.38%])



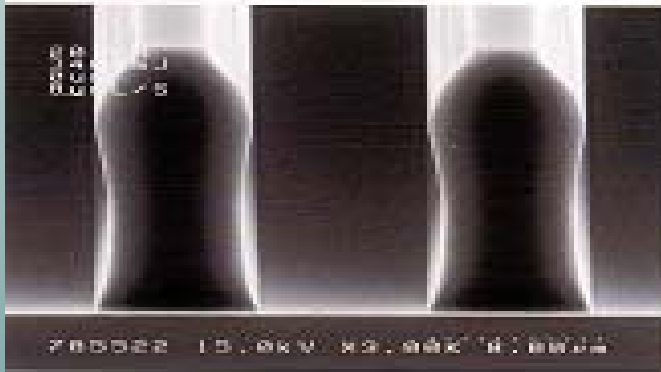
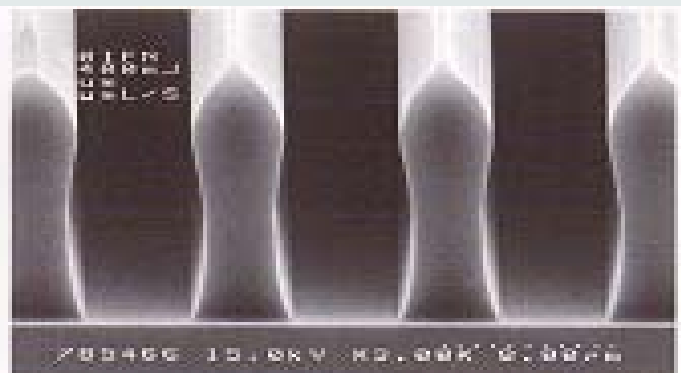
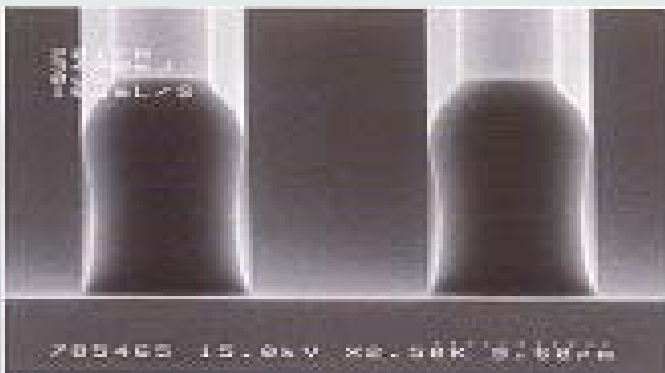
Film Thickness: 10μm Prebake: 100°C x 120 sec
 Exp.: NSR-TFH1 (NA = σ = 0.60 600mJ/cm²)
 PEB: none Focus : 0μm Mask size: 10, 5, 4, 3, 2, 1.5μm L/S
 Dev.: 50 sec x 5 (SSFO-238 [TMAH = 2.38%])



Film Thickness: 20 μ m Prebake: 110°Cx300 sec
 Exp.: G-line NSR-TFHI (NA = 0.22, σ = 0.60)
 I-line NSR-1755i7A (NA = 0.60, σ = 0.60)
 PEB: none Focus : 0 μ m
 Dev.: 50 sec x 10 (SSFD-238 [TMAH = 2.38%])



Film Thickness: 20 μ m Prebake: 110°C x 300 sec
Exp.: NSR-1755i7A (NA = 0.50, σ = 0.60) 3400mJ/cm²
PEB: none Focus : 0 μ m
Dev.: 50 sec x 10 (SSFD-238 [TMAH = 2.38%])



Film Thickness: 20 μ m Prebake: 110°Cx300 sec

Exp.: NSR-tfh1 (NA = 0.22, σ = 0.60) 1500mJ/cm²

PEB: none Focus : 0 μ m Mask size: 10,8,6,5,4,3 μ m L/S

Dev.: 50 sec x 10 (SSFD-238 [TMAH = 2.38%])

